



AF / IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Yoshiaki TANIDA et al.**

Group Art Unit: **2822**

Application No.: **10/614,227**

Corres. and Mail

Examiner: **Monica Lewis**

Filed: **July 8, 2003**

**BOX AF**

Confirmation No.: **6141**

For: **SEMICONDUCTOR DEVICE HAVING LOW INTERFACE STATE  
DENSITY AND METHOD FOR FABRICATING THE SAME**

Attorney Docket Number: **030823**

Customer Number: **38834**

**RESPONSE UNDER 37 C.F.R. § 1.116**  
**EXPEDITED PROCESSING REQUESTED**

**BOX AF**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Date: May 10, 2005

Sir:

In response to the Final Office Action dated February 10, 2005, Applicants amend the claims as follows and submit the following remarks.

Amendments to the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.